

**INFORMATION DISCLOSURE STATEMENT**

Applicant : Taku Hirayama  
App. No : 10/590,046  
Filed : June 15, 2007  
For : BASE MATERIAL FOR PATTERN-  
FORMING MATERIAL, POSITIVE  
RESIST COMPOSITION AND  
METHOD OF RESIST PATTERN  
FORMATION  
Examiner : Connie P. Johnson  
Art Unit : 1795

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing 3 (three) references to be considered by the Examiner.

This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required. If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 7/28/09

By: 

Neil S. Bartfeld, Ph.D.  
Registration No. 39,901  
Agent of Record  
Customer No. 20,995  
(619) 235-8550